

IN THE CLAIMS

Please cancel Claims 3-8 without prejudice or disclaimer of subject matter.

Please add Claims 15-19 to read as follows.

1. (Previously Presented) A patterning method comprising the steps of:

preparing a liquid discharge head comprising a discharge port for discharging liquid, a pressure-applying portion communicating with the discharge port, for applying a pressure for discharge to liquid, and a pressure-generating device for generating the pressure; and

applying liquid to a liquid-receiving member supported on a support by driving the liquid discharge head,

wherein said step of applying liquid comprises a step of applying a first discharge pulse for discharging liquid and a second discharge pulse for discharging liquid to the pressure-generating device in a sequential manner in response to an instruction of one-dot discharge, and

wherein a pulse width T_1 of the first discharge pulse, a pulse width T_2 of the second discharge pulse, and a rest time K_{12} between the first discharge pulse and the second discharge pulse are determined so that a first amount of liquid discharged in response to the first discharge pulse has a volume equal to or greater than that of a second amount of liquid discharged in response to the second discharge pulse and a discharge speed of the first amount of liquid is lower than a discharge speed of the second amount of liquid.

2. (Previously Presented) A patterning method according to claim 1, wherein the pulse width T_1 of the first discharge pulse, the pulse width T_2 of the second discharge pulse, and the rest time K_{12} are determined based on a hydrodynamic resonant frequency of the liquid discharge head.

3-14. (Canceled)

15. (New) A method of manufacturing an article of printed matter using a patterning method according to claim 1.

16. (New) A method of manufacturing a color filter using a patterning method according to claim 1.

17. (New) A method of manufacturing a thin film transistor using a patterning method according to claim 1.

18. (New) A method of manufacturing a light-emitting device using a patterning method according to claim 1.

19. (New) A method of manufacturing a DNA device using a patterning method according to claim 1.